

## EAST Search History

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L1	16	carr-jeffrey-w.in.	US-PGPUB; USPAT; USOCR; JPO; DERWENT; IBM_TDB	OR	ON	2006/07/07 10:17
L2	1	pattern and (CMP or "chemical mechanical polishing") and shadow and (peripheral or circumference) and boundarie and corner and polish\$4. clm.	US-PGPUB	OR	ON	2006/07/07 10:20
L3	4	yu-tu-hao.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/07/07 10:20
L4	6	sun-pai-hsuan.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/07/07 10:21
L5	14	chen-yu-chen.in.	US-PGPUB; USPAT; USOCR; EPO; JPO; DERWENT; IBM_TDB	OR	ON	2006/07/07 10:21